

**IN THE UNITED STATES PATENT AND TRADEMARK OFFICE**

Applicant:	YOUNG HOON PARK, ET AL.	)	
		)	Group Art Unit: 1762
Serial No.:	10/716,950	)	
		)	
Filed:	November 19, 2003	)	Examiner:
		)	Stouffer, Kelly M.
For:	METHOD OF DEPOSITING THIN FILM	)	
	USING ALUMINUM OXIDE	)	Confirmation No. 7281

**RESPONSE TO FINAL OFFICE ACTION**

Mail Stop AF

Commissioner for Patents  
P.O. Box 1450  
Alexandria, VA 22313-1450

Dear Sir:

Applicants respectfully request entry of the following amendment and remarks contained herein in response to the Final Office Action mailed December 12, 2006. Applicants respectfully submit that the remarks contained herein place the instant application in condition for allowance.

**Remarks** begin on page 2 of this paper.